

PROCEEDINGS OF SPIE

Advances in Metrology for X-Ray and EUV Optics II

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30 August 2007

San Diego, California, USA

Sponsored and Published by

SPIE

Volume 6704

Proceedings of SPIE, 0277-786X, v. 6704

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Author(s), "Title of Paper," in *Advances in Metrology for X-Ray and EUV Optics II*, edited by Lahsen Assoufid, Peter Z. Takacs, Masaru Ohtsuka, Proceedings of SPIE Vol. 6704 (SPIE, Bellingham, WA, 2007)
Article CID Number.

ISSN 0277-786X
ISBN 9780819468529

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org

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Printed in the United States of America.

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